

May 9, 2006



Applicants: O

OHMOTO et al

Serial No.:

10/663,646

Filed:

September 17, 2003

For:

Plasma Processing Apparatus

Art Unit:

1763

Examiner:

R. Dhingra

## <u>AMENDMENT</u>

Mail Stop: Amendment (Fee) Commissioner For Patents P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

The following amendments and remarks are respectfully submitted in connection with the accompanying RCE of the above-identified application, in response to the Office Action dated February 14, 2006. The amendments are listed below and set forth on the following pages.

Amendments to the Claims; and

Remarks are included following the amendments.